Optopro™ *622-EDU*

DYNAMIC 3D MEMS PROFILER

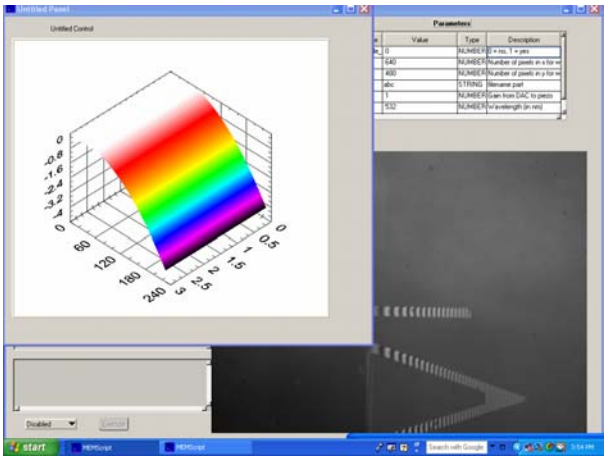
Low Cost MEMS Profiler for Microsystems Training

Provides affordable, easy to use, state-of-the-art, instrument configured specifically for educational institutions

Applications
Static & dynamic testing of MEMS devices
Phase shifting interferometry (PSI)

Main Features & Benefits
Long working-distance for probe clearance
Ability to make measurements through windows
Uses standard 10X microscope objectives
Premium-quality measurements at an affordable price
Fully upgradeable to Model 622-A specifications
State-of-the-art design

MEMScript™ software, which is an interpretive scripting environment, is provided with each ***Optopro*™ *622-EDU*** 3D MEMS profiler. ***MEMScript***™ has several unique features. In addition to analysis features, ***MEMScript***™ also has the ability to control MEMS devices and make real time measurements of performance.



***MEMScript*™ Software Features**
Phase shifting interferometry (PSI)
Arbitrary waveform output
Decision making capability (full logical branching)
Stroboscopic imaging capabilities
Concise user interface
Light source brightness autosetting
GPIB capabilities to interface with external equipment
Serial port capabilities to interface with external equipment
Compatible with ***Intelliwave***™ Software
Interface with MATLAB™, IDL™, MS Excel ™, and LabVIEW™

EMOpto.com™ nano-tools

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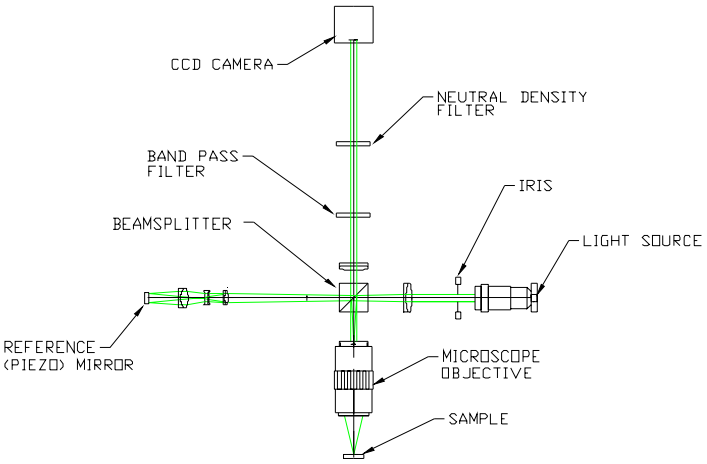
Optopro™ 622-EDU
3D MEMS PROFILER

Optopro™ 622-EDU SPECIFICATIONS			
Technology	Patented Long Working-Distance Interference Mircroscope		
System			
Test Beam	532 nm incoherent light source		
Magification	10X (5X and 20X optional)		
Camera	2/3" B&W Analog Camera		
Probe Micropositioners	Signatone (QTY:2)		
Voltage Amplifier	EMOpto 1, 2 or 4 channel (optional)		
Vibration Isolation	Breadboard with vibration isolation feet		
Vacuum/Shutter	None		
Part Viewing	Live video on computer screen		
Objective Lenses			
Magnification Numerical Aperture		10X 0.28	
Working Distance (mm)		33.5	
Focal Length (mm)		20	
Resolving Power (µm)		1.0	
Depth of Focus (µm)		3.5	
In-Plane Resolution (nm)		10	
Focus Resolution (nm)		+/- 5	
Field of View[1] - V x H		0.66 x 0.88	
Note 1: for 2/3 inch CCD.			
Electrical			
Power	Powered from Computer		
Mechanical			
Dimensions	762 mm x 610 mm x 762 mm (30" x 24" x 30")		
Weight	50 kg (110 lb)		
Environmental Req.			
Temperature	15 to 30ºC (59 to 86ºF)		
Rate of Temp. Change	<1.0ºC per 15 min		
Humidity	Relative 5% to 95%, no condensing		
Vibration Isolation			
Control			
Computer	Dell PC		
Interface	National Instruments		
Software	MEMScript™		



Optional Voltage Amplifier

Optional Vacuum Source & Shutter Control

Optional 4-Position Objective Lens Turrett

Optional VSI Controller with long-travel, Closed-Loop Piezo Actuator

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